

41. (Amended) An optical evaluation method for evaluating processing performed with respect to a substrate having a semiconductor region in a chamber, said method comprising the steps of:

supplying measurement light to the semiconductor region of said substrate in said chamber;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change of a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein said processing is a plasma etching process performed with respect to said semiconductor region.

42. (Amended) An optical evaluation method for evaluating processing performed with respect to a substrate having a semiconductor region in a chamber, said method comprising the steps of:

supplying measurement light to the semiconductor region of said substrate in said chamber;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change of a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

D1 wherein said processing is a light dry etching process for removing a damaged layer caused by plasma etching performed with respect to said semiconductor region.

43. (Amended) An optical evaluation method for evaluating processing performed with respect to a substrate having a semiconductor region in a chamber, said method comprising the steps of:

C1 supplying measurement light to the semiconductor region of said substrate in said chamber;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change of a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein said processing is a process of introducing an impurity into said semiconductor region.

44. (Amended) An optical evaluation method for evaluating processing performed with respect to a substrate having a semiconductor region in a chamber, said method comprising the steps of:

supplying measurement light to the semiconductor region of said substrate in said chamber;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change of a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein said processing is an annealing process performed after impurity ions are implanted in said semiconductor region.

45. (Amended) An optical evaluation method for evaluating processing performed with respect to a substrate having a semiconductor region in a chamber, said method comprising the steps of:

supplying measurement light to the semiconductor region of said substrate in said chamber;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change of a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein said processing is a process of forming an insulating film on said semiconductor region.

46. (Amended) An optical evaluation method for evaluating processing performed with respect to a substrate having a semiconductor region in a chamber, said method comprising the steps of:

supplying measurement light to the semiconductor region of said substrate in said chamber;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change of a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein said processing is a dry etching process for removing an insulating film from a top surface of said semiconductor region.

47. (Amended) An optical evaluation method for evaluating processing performed with respect to a substrate having a semiconductor region in a chamber, said method comprising the steps of:

supplying measurement light to the semiconductor region of said substrate in said chamber;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change of a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein said semiconductor region is composed of n-type silicon.

48. (Amended) An optical evaluation method for evaluating processing performed with respect to a substrate having a semiconductor region in a chamber, said method comprising the steps of:

supplying measurement light to the semiconductor region of said substrate in said chamber;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change of a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein said exciting light is intermittently emitted at a frequency of 1 kHz or less in said step of supplying the exciting light.

50. (Amended) A method of manufacturing a semiconductor device according to claim 49, wherein said second step includes the steps of:

supplying measurement light to said semiconductor region;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change of a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light.

51. (Amended) A method of manufacturing a semiconductor device according to claim 50, wherein the change in ratio of the reflectance of the measurement light of a wavelength of 600 nm or less is calculated in said step of calculating the change in ratio of the reflectance.

52. (Amended) A method of manufacturing a semiconductor device according to claim 51, wherein the change in ratio of the reflectance of the measurement light of a wavelength of 300 to 600 nm is calculated in said step of calculating the change in ratio of the reflectance.

53. (Amended) A method of manufacturing a semiconductor device according to claim 50, wherein the change in ratio of the reflectance of the measurement light at a specified energy value of the measurement light which provides a near extremal value in a spectrum of the change in ratio of the reflectance of the measurement light is calculated in said step of calculating the change in ratio of the reflectance.

62. (Amended) A method of manufacturing a semiconductor device according to claim 50, said method further comprising, prior to said second step, the steps of:

introducing an impurity at a high concentration into said semiconductor region of said substrate and depositing an interlayer insulating film on said semiconductor region; and

selectively removing said interlayer insulating film by plasma etching to form an opening reaching said semiconductor region,

wherein said third step includes performing light dry etching with respect to the semiconductor region exposed at a bottom surface of said opening to remove a damaged layer caused by said plasma etching and predetermining a proper range of the change in ratio of the

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reflectance of said measurement light when an electric property of the semiconductor region is proper and

said fourth step includes performing said light dry etching such that said change in ratio of the reflectance falls within said proper range.

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68. (Amended) A method of manufacturing a semiconductor device according to claim 50, wherein said second step includes evaluating the change in ratio of the reflectance of measurement light by using an ellipsometric-spectroscope.

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73. (Amended) A method of manufacturing a semiconductor device having a semiconductor region with a structural disorder developed therein, said method comprising the steps of:
evaluating an optical property of said semiconductor region; and
performing a heat treatment for recovering said semiconductor region from the structural disorder, while controlling a condition for the heat treatment based on the optical property of said semiconductor region evaluated in said foregoing step;

said step of evaluating the optical property includes the steps of:
supplying measurement light to said semiconductor region;
intermittently supplying exciting light to said semiconductor region; and
calculating a rate of change in a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the

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presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein the change in ratio of the reflectance of the measurement light at a specified energy value of the measurement light which provides a near extremal value in a spectrum of the change rate of the reflectance of the measurement light is calculated in said step of calculating the change in ratio of the reflectance.

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74. (Amended) A method of manufacturing a semiconductor device having a semiconductor region with a structural disorder developed therein, said method comprising the steps of:

evaluating an optical property of said semiconductor region; and

performing a heat treatment for recovering said semiconductor region from the structural disorder, while controlling a condition for the heat treatment based on the optical property of said semiconductor region evaluated in said foregoing step;

said step of evaluating the optical property includes the steps of:

supplying measurement light to said semiconductor region;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change in a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein the change in ratio of the reflectance of the measurement light of a wavelength of 500 nm or less is calculated in said step of calculating the change in ratio of the reflectance

and said specified energy value of the measurement light is any value included in a range of 3.2 to 3.6 eV.

75. (Amended) A method of manufacturing a semiconductor device having a semiconductor region with a structural disorder developed therein, said method comprising the steps of:

evaluating an optical property of said semiconductor region; and

performing a heat treatment for recovering said semiconductor region from the structural disorder, while controlling a condition for the heat treatment based on the optical property of said semiconductor region evaluated in said foregoing step;

said step of evaluating the optical property includes the steps of:

supplying measurement light to said semiconductor region;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change in a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein said exciting light is intermittently emitted at a frequency of 1 kHz or less in said step of supplying the exciting light.

76. (Amended) A method of manufacturing a semiconductor device having a semiconductor region with a structural disorder developed therein, said method comprising the steps of:

evaluating an optical property of said semiconductor region; and
 performing a heat treatment for recovering said semiconductor region from the structural disorder, while controlling a condition for the heat treatment based on the optical property of said semiconductor region evaluated in said foregoing step;

said step of evaluating the optical property includes the steps of:

supplying measurement light to said semiconductor region;
 intermittently supplying exciting light to said semiconductor region; and
 calculating a rate of change in a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein a proper range of the change in ratio of the reflectance of said measurement light when an electric property of the semiconductor region is proper is predetermined, and

said heat treatment is performed in said step of performing the heat treatment with respect to the semiconductor region such that the change in ratio of the reflectance of said measurement light falls within said proper range.

77. (Amended) A method of manufacturing a semiconductor device having a semiconductor region with a structural disorder developed therein, said method comprising the steps of:

evaluating an optical property of said semiconductor region; and

performing a heat treatment for recovering said semiconductor region from the structural disorder, while controlling a condition for the heat treatment based on the optical property of said semiconductor region evaluated in said foregoing step;

said step of evaluating the optical property includes the steps of:

supplying measurement light to said semiconductor region;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change in a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein a relationship between the change in ratio of the reflectance of the measurement light in said semiconductor region and an impurity concentration in said semiconductor region is predetermined, and

the heat treatment is performed with respect to said semiconductor device in said step of performing the heat treatment till the change in ratio of the reflectance of the measurement light in said semiconductor region reaches a value corresponding to a desired impurity concentration.

78. (Amended) A method of manufacturing a semiconductor device having a semiconductor region with a structural disorder developed therein, said method comprising the steps of:

evaluating an optical property of said semiconductor region; and

performing a heat treatment for recovering said semiconductor region from the structural disorder, while controlling a condition for the heat treatment based on the optical property of said semiconductor region evaluated in said foregoing step;

wherein a first semiconductor region forming a part of a semiconductor element and a second semiconductor region to be subjected to optical evaluation are preliminarily formed as said semiconductor region,

the optical property of said second semiconductor region is evaluated in said step of evaluating the optical property, and

said first and second semiconductor regions are simultaneously subjected to the heat treatment in said step of performing the heat treatment, while a condition for said heat treatment is controlled based on the result of evaluating the optical property of said second semiconductor region.

80. (Amended) A method of manufacturing a semiconductor device having a semiconductor region with a structural disorder developed therein, said method comprising the steps of:

evaluating an optical property of said semiconductor region; and

performing a heat treatment for recovering said semiconductor region from the structural disorder, while controlling a condition for the heat treatment based on the optical property of said semiconductor region evaluated in said foregoing step;

wherein a portion of said semiconductor region to be subjected to optical evaluation is composed of n-type silicon.

81. (Amended) A method of manufacturing a semiconductor device having a semiconductor region with a structural disorder developed therein, said method comprising the steps of:

evaluating an optical property of said semiconductor region; and

performing a heat treatment for recovering said semiconductor region from the structural disorder, while controlling a condition for the heat treatment based on the optical property of said semiconductor region evaluated in said foregoing step;

wherein a portion of said semiconductor region to be subjected to optical evaluation is composed of n-type silicon.

82. (Amended) A method of manufacturing a semiconductor device having a semiconductor region with a structural disorder developed therein, said method comprising the steps of:

evaluating an optical property of said semiconductor region; and

performing a heat treatment for recovering said semiconductor region from the structural disorder, while controlling a condition for the heat treatment based on the optical property of said semiconductor region evaluated in said foregoing step;

said step of evaluating the optical property includes the steps of:

supplying measurement light to said semiconductor region;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change in a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the

presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light,

wherein said second step includes evaluating the change in ratio of the reflectance of the measurement light by using an ellipsometric spectroscope.

84. (Amended) A method of manufacturing a semiconductor device according to claim 83, wherein said step of evaluating the optical property includes the steps of:

supplying measurement light to said semiconductor region;

intermittently supplying exciting light to said semiconductor region; and

calculating a rate of change in a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light.

85. (Amended) A method of manufacturing a semiconductor device according to claim 84, wherein the change in ratio of the reflectance of the measurement light of a wavelength of 600 nm or less is calculated in said step of calculating the change in ratio of the reflectance.

86. (Amended) A method of manufacturing a semiconductor device according to claim 85, wherein the change in ratio of the reflectance of the measurement light of a wavelength of 300 to 600 nm is calculated in said step of calculating the change in ratio of the reflectance.

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87. (Amended) A method of manufacturing a semiconductor device according to claim 84, wherein the change in ratio of the reflectance of the measurement light at a specified energy value of the measurement light which provides a near extremal value in a spectrum of the change rate of the reflectance of the measurement light is calculated in said step of calculating the change in ratio of the reflectance.

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90. (Amended) A method of manufacturing a semiconductor device according to claim 84, wherein:

a relationship between an amount of introduced impurity and the change in ratio of the reflectance of said measurement light is predetermined by experiment, and
said impurity is introduced in said step of introducing the impurity into said semiconductor region such that the change in ratio of the reflectance of said measurement light reaches a value corresponding to a desired amount of introduced impurity.

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95. (Amended) A method of manufacturing a semiconductor device according to claim 84, wherein said second step includes evaluating the change in ratio of the reflectance of the measurement light by using an ellipsometric spectroscopy.

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97. (Amended) A method of manufacturing a semiconductor device according to claim 96, wherein said second step includes the steps of:
supplying measurement light to said semiconductor region;
intermittently supplying exciting light to said semiconductor region; and

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calculating a rate of change in a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light.

98. (Amended) A method of manufacturing a semiconductor device according to claim 97, wherein the change in ratio of the reflectance of the measurement light of a wavelength of 600 nm or less is calculated in said step of calculating the change in ratio of the reflectance.

99. (Amended) A method of manufacturing a semiconductor device according to claim 98, wherein the change in ratio of the reflectance of the measurement light of a wavelength of 300 to 600 nm is calculated in said step of calculating the change in ratio of the reflectance.

100. (Amended) A method of manufacturing a semiconductor device according to claim 97, wherein the change in ratio of the reflectance of the measurement light at a specified energy value of the measurement light which provides a near extremal value in a spectrum of the change rate of the reflectance of the measurement light is calculated in said step of calculating the change in ratio of the reflectance.

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103. (Amended) A method of manufacturing a semiconductor device according to claim 97, wherein:
a proper range of the change in ratio of the reflectance of the measurement light when an electric property of the insulating film is proper is predetermined by experiment, and

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said fourth step includes forming the insulating film such that the change in ratio of the reflectance of the measurement light measured in said second step falls within said proper range.

104. (Amended) A method of manufacturing a semiconductor device according to claim 97, wherein:

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said second step includes measuring the change in ratio of the reflectance of the measurement light in the semiconductor region before said insulating film is formed thereon, and

said fourth step includes controlling a condition for the formation of the insulating film by remeasuring the change in ratio of the reflectance of the measurement light in said semiconductor region which varies with the progression of the formation of the insulating film and comparing a result of remeasurement with a result of measurement performed in said second step.

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108. (Amended) A method of manufacturing a semiconductor device according to claim 97, said method further comprising, after said fourth step, the step of:

judging the formed insulating film to be good or no good based on a relationship predetermined by experiment between the change in ratio of the reflectance of said measurement light and an electric property of the insulating film.

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111. (Amended) A method of manufacturing a semiconductor device according to claim 97, wherein said second step includes evaluating the change in ratio of the reflectance of the measurement light by using an ellipsometric spectroscopy.

113. (Amended) A method of manufacturing a semiconductor device according to claim 112, wherein said second step includes the steps of:

supplying measurement light to said semiconductor region through said insulating film; intermittently supplying exciting light to said semiconductor region through said insulating film; and

calculating a rate of change in a ratio of a reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light.

114. (Amended) A method of manufacturing a semiconductor device according to claim 113, wherein the change in ratio of the reflectance of the measurement light of a wavelength of 600 nm or less is calculated in said step of calculating the change in ratio of the reflectance.

115. (Amended) A method of manufacturing a semiconductor device according to claim 114, wherein the change in ratio of the reflectance of the measurement light of a wavelength of 300 to 600 nm is calculated in said step of calculating the change in ratio of the reflectance.

116. (Amended) A method of manufacturing a semiconductor device according to claim 113, wherein the change in ratio of the reflectance of the measurement light at a specified energy value of the measurement light which provides a near extremal value in a spectrum of the change in ratio of the reflectance of the measurement light is calculated in said step of calculating the change in ratio of the reflectance.

119. (Amended) A method of manufacturing a semiconductor device according to claim 113, wherein:

a proper range of the change in ratio of the reflectance of the measurement light when the removal of said insulating is properly completed is predetermined, and

said fourth step includes performing dry etching with respect to the insulating film such that the change in ratio of the reflectance of the measurement light measured in said second step falls within said proper range.

120. (Amended) A method of manufacturing a semiconductor device according to claim 113, wherein:

said second step includes measuring the change in ratio of the reflectance of the measurement light in the semiconductor region when said insulating film is formed thereon, and

said fourth step includes controlling a condition for the removal of the insulating film by remeasuring the change in ratio of the reflectance of the measurement light in said semiconductor region which varies with the progression of the removal of the insulating film and comparing a result of remeasurement with a result of measurement performed in said second step.

127. (Amended) A method of manufacturing a semiconductor device according to claim 113, wherein said second step includes evaluating the change in ratio of the reflectance of the measurement light by using an ellipsometric spectroscope.

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128. (Amended) A method of controlling an apparatus for manufacturing a semiconductor device comprising a chamber for containing a substrate having a semiconductor region, processing means for performing processing with respect to said substrate in said chamber, first light supplying means for intermittently supplying exciting light to the semiconductor region of said substrate placed in said chamber, a second light supplying means for supplying measurement light to said semiconductor region, and reflectance measuring means for measuring a reflectance of the measurement light supplied to said semiconductor region, said method comprising :

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- a first step of supplying the measurement light to said semiconductor region;
- a second step of intermittently supplying the exciting light to said semiconductor region;
- a third step of calculating a rate of change of a ratio of the reflectance of the measurement light by dividing a difference between the respective reflectances of the measurement light in the presence and absence of said exciting light supplied to said semiconductor region by the reflectance of the measurement light in the absence of the exciting light;
- a fourth step of operating said processing means for a specified time till the change rate of the reflectance calculated in said third step reaches a specified value; and
- a fifth step of monitoring said specified time in said fourth step and outputting a signal for causing maintenance to be performed with respect to said apparatus for manufacturing the semiconductor device when said specified time exceeds a limit value.

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137. (Amended) A method of controlling an apparatus for manufacturing a semiconductor device according to claim 128, wherein the change in ratio of the reflectance of the measurement light at a specified energy value of the measurement light which provides a